

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of Berry et al.

Group Art Unit: 2814

Serial No.: 09/505,695

Examiner: Le, Thao X.

Confirmation No.: 6935

Filed: February 17, 2000

For: Method of Photoresist Ash Residue
Removal

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

PETITION FOR EXTENSION OF TIME

Sir:

The following one-month extension of time is requested to November 11, 2003;
the extension fee is:

☐ \$55.00 ☒ \$110.00

- ☒ An extension fee in the amount of \$110.00 is enclosed.
- ☐ The shortened statutory period has been reset by an Advisory Action dated
- ☐ Charge \$ to Deposit Account No. 05-0460.
- ☒ The Commissioner is hereby authorized to charge any additional appropriate fees under 37 C.F.R. §§ 1.16, 1.17 and 1.21 that may be required by this paper, and to credit any overpayment, to Deposit Account No. 05-0460. This paper is submitted in duplicate.

11/06/2003 CNGUYEN 00000089 09505695

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110.00 OP

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OCT 10 2003
TECHNOLOGY CENTER 2800


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NOV 10 2003
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Dated: 11/4/03

EDELL, SHAPIRO & FINNAN, LLC
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(301) 424-3640

Respectfully submitted by
EDELL, SHAPIRO & FINNAN, LLC

By:



Martin Abramson
Reg. No. 25,787